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## \*BIBDATASHEET\*

**Bib Data Sheet** 

**CONFIRMATION NO. 8557** 

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APPLICANTS			•		
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** CONTINUING DAT	A MK (NONE)	*			
JAPAN 2002-29 JAPAN 2003-00 IF REQUIRED, FORE	ATIONS	GRANTED			
** 11/21/2003 Foreign Priority claimed	⊠ <sub>yes</sub> □ <sub>no</sub>		1	<u> </u>	1
35 USC 119 (a-d) conditions	s 🛛 yes 🗆 no 🗆 Met afti Allowance	STATE OR	SHEETS	TOTAL	INDEPENDENT
met Verified and Acknowledged Exa		COUNTRY JAPAN	DRAWING 7	CLAIMS 4	CLAIMS 1
ADDRESS 22428 FOLEY AND LARDNE SUITE 500 3000 K STREET NW WASHINGTON , DC 20007	ER		·		
TITLE					
Silicon wafer cleaning	method				
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